# Scaled Model Measurement of the Embedding Impedance of a 660-GHz Waveguide SIS Mixer with a 3-Standard De-embedding Method W. Zhang<sup>1</sup>, C-.Y. Edward Tong<sup>2</sup> and S.C. Shi<sup>1</sup>

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**Abstract:** In this paper, the embedding impedance of a 660-GHz waveguide SIS (superconductor-insulator-superconductor) mixer is investigated using a 100-times scaled model with a new 3-standard de-embedding technique. The mixer embedding impedance is extracted from the reflection coefficients measured at the waveguide port of the mixer for three different terminations at the SIS junction's feed point. The three standards chosen are open-circuit, short-circuit and resistive load. Measured results are compared with those simulated by HFSS (High Frequency Structure Simulator).

#### 1. Introduction

For the design of fixed-tuned waveguide SIS mixers in the submillimeter regime, it is necessary to have a precise knowledge of the mixer embedding impedance (i.e., the impedance seen at the junction's feed point). Embedding impedances have been determined using scaled-model measurement [1] or numerical methods [2]. The conventional scaled-model method measures the embedding impedance directly via a miniature coaxial connected to the junction's feed point. The accuracy of this method is limited by the model accuracy of the coaxial probe's tip. Numerical methods that derive impedances from the pumped I-V curves of SIS junctions depend largely upon junction parameters. Full-wave electromagnetic solvers, like HFSS, have been used to model a few submillimeter mixers [3]. However, it is important to have experimental confirmation of simulated data.

In this paper, we propose a new scaled-model measurement method, which incorporates a 3-standard de-embedding technique [4]. This technique extracts the scattering parameters of a two-port network from the reflection coefficients measured at one port when the second port is terminated with 3 different

impedance standards. Using this new method, we have determined the embedding impedance of a 600-720 GHz waveguide SIS mixer mount [5] with a 100-times scaled model. The measured impedances are then compared with those simulated by HFSS.

## 2. Measurement method

Fig. 1 shows the fabricated 100-times scaled model. Its operating frequency was 6.0-7.2 GHz scaled down from 600-720 GHz. The crystalline quartz substrate was replaced by a 4-mm thick dielectric slab ( $\varepsilon_r \sim 3.5$ ), and the junction's feed point was scaled to a gap (0.2x1 mm). In our measurements, the feed point was connected to 3 different calibration standards:



Fig. 1 100-times scaled model for a 660-GHz waveguide SIS mixer mount, (a) overall view of the model, (b) photograph of the dielectric slab used inside the model

open-circuit, short-circuit and resistive load given by chip resistors (0.5x1 mm). A waveguide-to-coaxial transition was included to interface to a microwave network analyzer.

First, we measured the complex reflection coefficients at the coaxial port of the waveguide-to-coaxial transition, while its waveguide port was shorted. Let  $\Gamma_m$  (m=1, 2, 3) be the measured reflection coefficients corresponding to 3 different short circuit planes, and [S'] the scattering matrix of the transition. The relation between  $\Gamma_m$  and [S'] is

$$\Gamma_m = S_{11}^t + \left\{ S_{12}^t S_{21}^t R_m / \left( 1 - S_{22}^t R_m \right) \right\},\tag{1}$$

where  $R_m$  is the complex reflection coefficient of the waveguide short circuit *m* at the waveguide port. [S'] can be easily solved using Equation (1) [4].

Next, we connected the transition to the scaled mixer block and the complex reflection coefficients were measured again at the coaxial port of the transition while the device feed point was terminated by the three calibration standards. Let  $\Gamma_i$  be the measured complex reflection coefficient when the junction's feed point was terminated by calibration standard *i*, where i = o (open), *s* (short) or *r* (resistive). Let  $\Gamma_i$ ' be the corresponding reflection coefficient at the mixer's waveguide port when the port was terminated by a matched load instead of the transition. The relation between  $\Gamma_i$ ' and  $\Gamma_i$  is

$$\Gamma_{i}^{\prime} = \left(\Gamma_{i} - S_{11}^{\prime}\right) / \left\{S_{12}^{\prime}S_{21}^{\prime} + \left(\Gamma_{i} - S_{11}^{\prime}\right)S_{22}^{\prime}\right\}$$
(2)

The embedding impedance  $Z_{emb}$  at the device feed point can be solved in terms of  $\Gamma_i$ 

$$Z_{emb} = Z_r \left( \Gamma_o' - \Gamma_r' \right) / \left( \Gamma_r' - \Gamma_s' \right)$$
(3)

where  $Z_r$  is the impedance of the chip resistor at the measured frequency.

Equation (3) shows that the derived embedding impedance is directly proportional to  $Z_r$ . It is therefore very important to know the accurate value of this impedance. We have measured the actual impedances of these chip resistors in a separate experiment setup.

### 3. Measurement results

The impedances of three chip resistors, whose nominal resistances are 24, 51, and 100  $\Omega$ , were measured with a microstrip fixture (0.5 mm thick and 1.2 mm wide) having a 1-mm gap at its center where the chip resistor was to be soldered. Time-domain gating technique was employed to remove the discontinuity effect due to SMA connectors to microstrip line [6]. The loss and phase shift of the microstrip



Fig. 2 Measured impedances of three chip resistors.

Fig. 3 Measured embedding impedance of the 100-times scaled model for three instances.

line were also compensated. The measured impedances for the three chip resistors are plotted in Fig. 2. Obviously, the chip resistors have resistances close to their nominal values, but all have a considerably large positive reactance in the frequency range of 6-14 GHz. The larger the nominal resistance is, the smaller the measured reactance becomes. In addition, the measured reactance is proportional to frequency, suggesting that there is a series parasitic inductance.

The waveguide-to-coaxial transition had been designed with the aid of HFSS by optimizing its power transmission coefficient in the frequency range of 6.0-7.2 GHz. Using the procedure described above, we have measured the scattering parameters of the transition. It has been found that the measured  $S_{12}'$  values are in good agreement with the simulated ones.

Equations (2) and (3) were then used to determine the embedding impedance of the scaled 660-GHz SIS mixer. Three sets of data were available, one from each chip resistor. The results are plotted in Fig. 3. The embedding impedances, both real and imaginary parts, are in good agreement for the three instances. The dispersion of the 3 data sets is less than 7  $\Omega$ , averaged across 6.0–7.2 GHz. The embedding impedance simulated for the same structure by HFSS is also displayed in Fig. 3. Clearly, the simulated resistance differs slightly from the measured one and the simulated reactance shows better agreement with the measured one.

### 4. Summary

A new scaled-model measurement method incorporating the 3-standard de-embedding technique has been employed to characterize the embedding impedance of a 660-GHz waveguide SIS mixer. The impedances of the chip resistors used in our scaled-model measurement were accurately measured using the time-domain gating technique. By comparing the data dispersion between embedding impedances derived from different calibration standards, we infer that the measured impedances are accurate to within 7  $\Omega$ . These measured embedding impedances also agree with the numerically simulated ones. The new scaled-model method is very useful for the characterization of submillimeter mixer mounts.

#### References

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